

Atty.  
Dkt. No.

M#

Client Ref.

306399

P-0375.010-US

# **INFORMATION DISCLOSURE STATEMENT BY APPLICANT**

Applicant: Ralph KURT et al.

Appln. No.: Not Assigned

Filing Date: October 17, 2003

Date: October 17, 2003

Page

1

of

1

Examiner: Not Assigned

Group Art Unit: Not Assigned

## **U.S. PATENT DOCUMENTS**

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	2003/0095623	05/2003	SINGER et al.	378	34	
	BR	2002/0109828	08/2002	MOORS et al.	355	76	
	CR						
	DR						
	ER						
	FR						
	GR						
	HR						

## **FOREIGN PATENT DOCUMENTS**

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
							Enclosed	No	Enclose	No
	IR	EP 1223468	07/2002	European	KOSTER et al.				X	
	JR	EP 0987601	03/2000	European	KOMATSUDA et al.				X	
	KR	EP 1182510	02/2002	European	MOORS et al.				X	
	LR	WO 99/42904	08/1999	PCT	SHMAENOK				X	
	MR									
	NR									
	OR									
	PR									
	QR									
	RR									

## **OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

	SR	EP Search Report for EP 02079329.5 dated August 22, 2003								
	TR	William Partlo et al., "Development of an EUV (13.5 nm) Light Source Employing a Dense Plasma Focus in Lithium Vapor," Proc. of SPIE, Vol. 3997, pgs. 136-156 (2000).								
	UR	Malcolm W. McGeoch, "Power Scaling of a Z-Pinch Extreme Ultraviolet Source," Proc. of SPIE, Vol. 3997, pgs. 861-866 (2000).								
	VR	Klaus Bergmann et al., "Highly Repetitive, Extreme-Ultraviolet Radiation Source Based on a Gas-Discharge Plasma," Applied Optics, Vol. 38, pgs. 5413-5417 (1999).								
	WR									
	XR									

Examiner

Date Considered:

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.